

Analytical Modeling Framework for Short-Channel DG and GAA MOSFETs

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Overview

Objectives:

- Establish *framework for precise modeling* of short-channel nanoscale MOSFETs
- Establish *compact model expressions* with a minimal parameter set determined from the framework

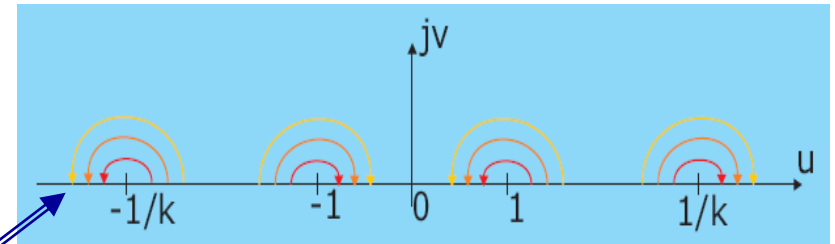
Procedure:

- ***Capacitive inter-electrode effects***
 - In *subthreshold*, find analytical 2D solution for DG potential distribution and drain current
 - Use DG solution to obtain GAA solution with high precision
- ***Near threshold***
 - Apply Poisson's equations, boundary conditions, and modeling expressions for calculating the potential distribution
 - Determine *self-consistently* the total *potential distribution* and the *drain current* by including electrostatic effects from electrons
- ***Strong inversion***
 - Use long-channel approximation



DG modeling details – subthreshold

- Include gate oxide in extended device body: $t'_{ox} = t_{ox}\epsilon_{ox}/\epsilon_{Si}$
- Map DG MOSFET body into upper half plane of transformed (u, iv) -plane using **conformal mapping** (Schwartz-Christoffel transform).
- **Subthreshold**: Solve Laplace's equation in (u, iv) -plane (low-doped body)
→ 2D potential distribution for capacitive coupling. Map back to (x, y) -plane

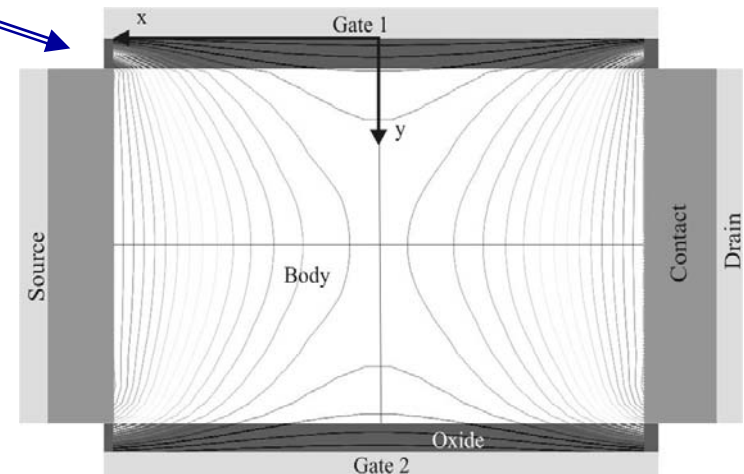


Schwartz-Christoffel transformation

$$z = x + iy = \frac{L}{2} \frac{F(k, u + iv)}{K(k)}$$

$$F(k, w) = \int_0^w \frac{dw'}{\sqrt{(1-w'^2)(1-k^2w'^2)}}, \quad K(k) = F(k, 1)$$

$$\varphi(u, v) = \frac{v}{\pi} \int_{-\infty}^{\infty} \frac{\varphi(u')}{(u'-u)^2 + v^2} du' = \frac{1}{\pi} \left\{ \begin{aligned} & (V_{GS2} - V_{FB}) \left[\pi - \tan^{-1}\left(\frac{1-ku}{kv}\right) - \tan^{-1}\left(\frac{1+ku}{kv}\right) \right] \\ & + (V_{GS1} - V_{FB}) \left[\tan^{-1}\left(\frac{1-u}{v}\right) + \tan^{-1}\left(\frac{1+u}{v}\right) \right] \\ & + V_{bi} \left[\tan^{-1}\left(\frac{1-ku}{kv}\right) - \tan^{-1}\left(\frac{1-u}{v}\right) \right] \\ & + (V_{bi} + V_{DS}) \left[\tan^{-1}\left(\frac{1+ku}{kv}\right) - \tan^{-1}\left(\frac{1+u}{v}\right) \right] \end{aligned} \right\}$$



GAA modeling details – subthreshold

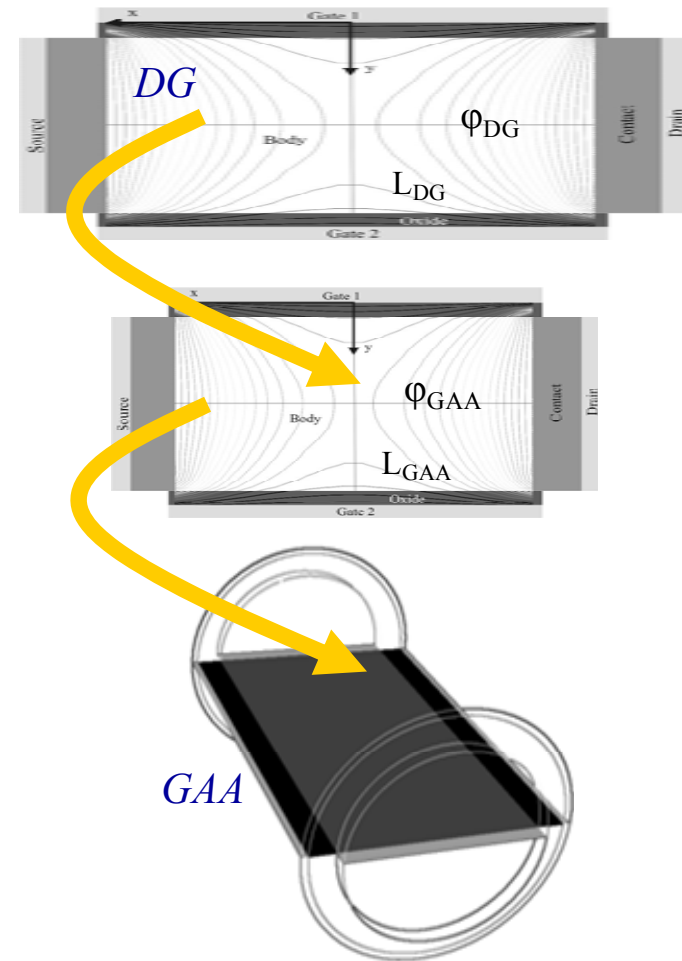
- Observe structural similarities with 2D DG MOSFET potential
- Major difference: Field penetration into body from S and D electrodes, determined by characteristic lengths:

$$\lambda_{DG} = \sqrt{\frac{\epsilon_{si}}{2\epsilon_{ox}} \left(1 + \frac{\epsilon_{ox} t_{si}}{4\epsilon_{si} t_{ox}}\right) t_{si} t_{ox}}, \quad \lambda_{GAA} = r_{si} \sqrt{\frac{1}{4} + \frac{\epsilon_{si}}{2\epsilon_{ox}} \ln\left(1 + \frac{t_{ox}}{r_{si}}\right)}$$

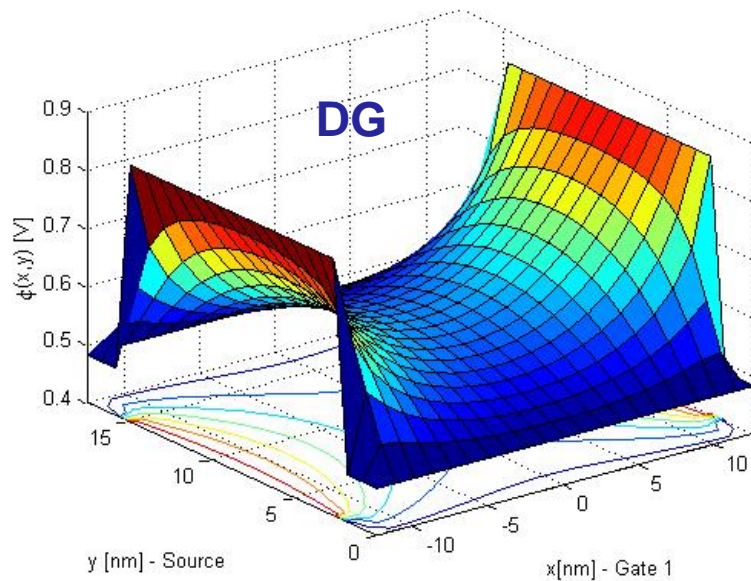
- Map ϕ_{DG} from device with length

$$L_{DG} = \frac{\lambda_{DG}}{\lambda_{GAA}} L_{GAA}$$

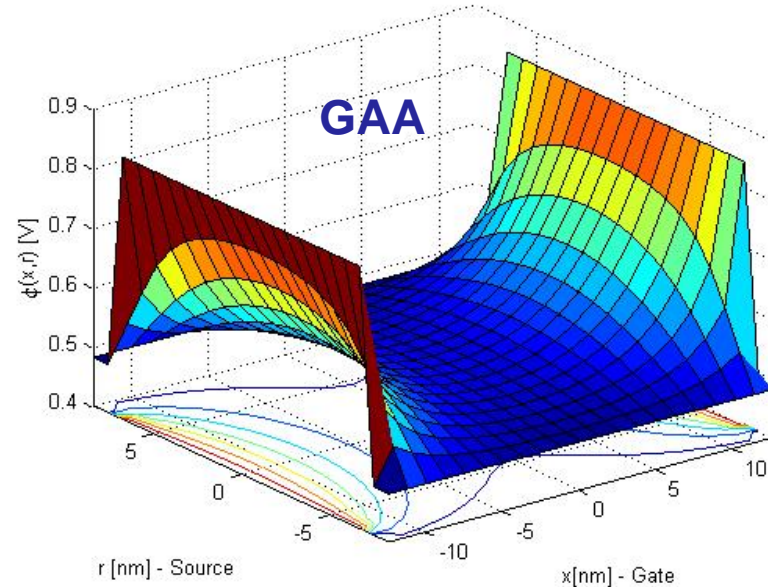
into GAA MOSFET body cross-section with length L_{GAA}



Subthreshold potential distributions



$$V_{GS} = V_{DS} = 0 \text{ V}$$

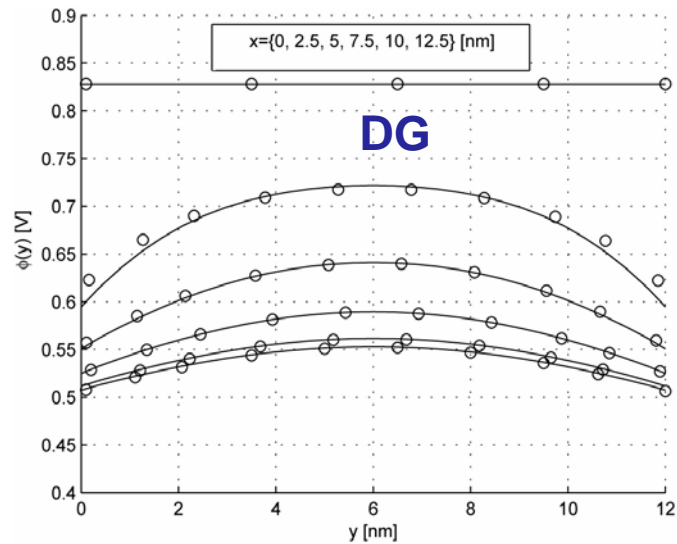


$$V_{GS} = V_{DS} = 0 \text{ V}$$

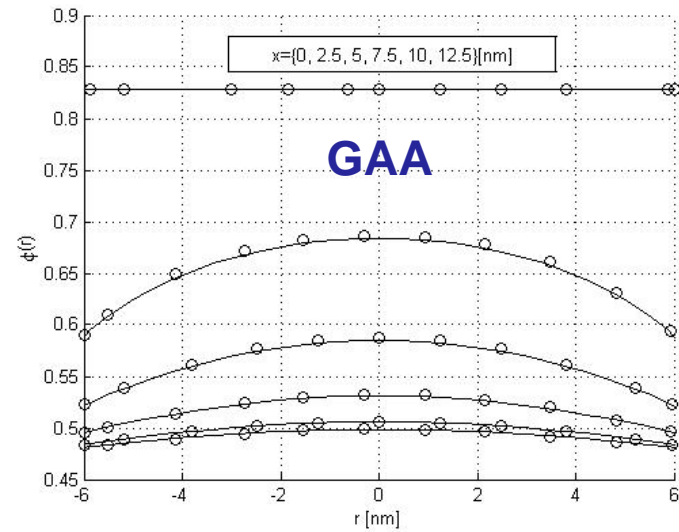
Devices considered: n-channel DG and GAA MOSFETs

Specifics: $L = 25 \text{ nm}$, $t_{si} = 12 \text{ nm}$, $t_{ox} = 1.6 \text{ nm}$, $\epsilon_{ox} = 7$, body doping $N_d = 10^{15} \text{ cm}^{-3}$, midgap gate metal $\phi_{msg} = 4.53 \text{ eV}$, 'metallic' source/drain contacts $\phi_{msc} = 4.17 \text{ eV}$ (as for n+ Si)

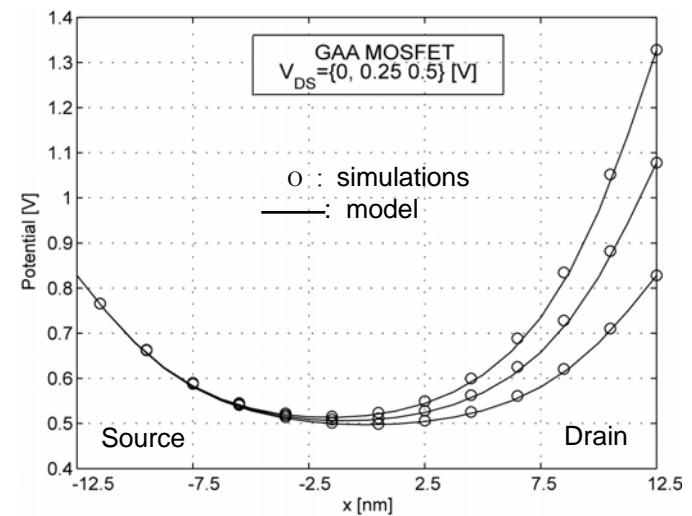
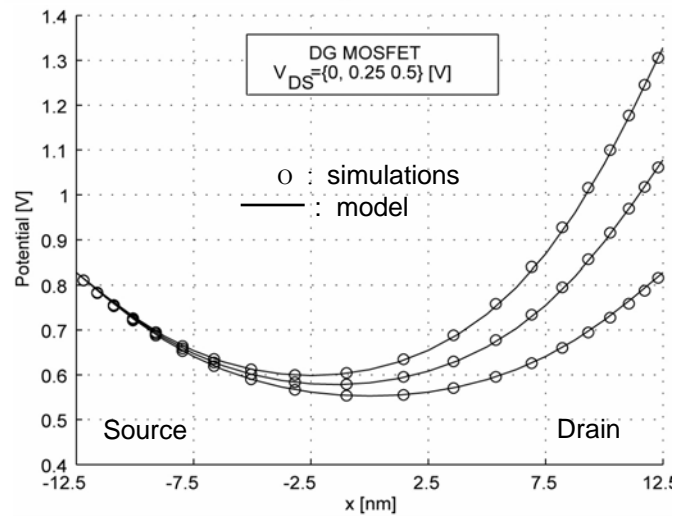
Subthreshold – verification



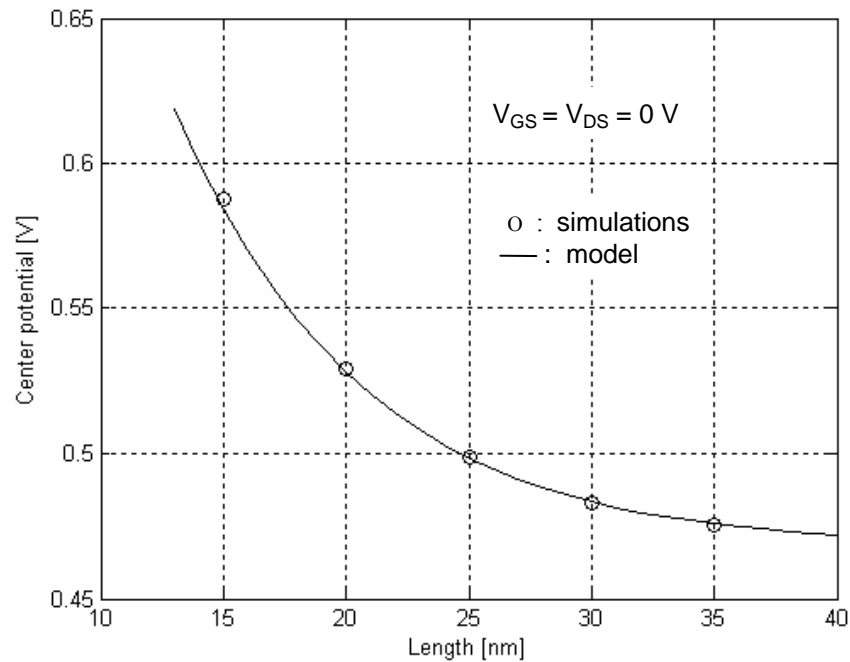
Subthreshold gate-to-gate pot. Profiles
 $V_{GS} = V_{DS} = 0$ V



Subthreshold source-to-drain pot. Profiles
 $V_{GS} = 0$ V



Scaling – center potential of GAA



Scaling of center potential with
gate length in subthreshold

Near threshold – self-consistency

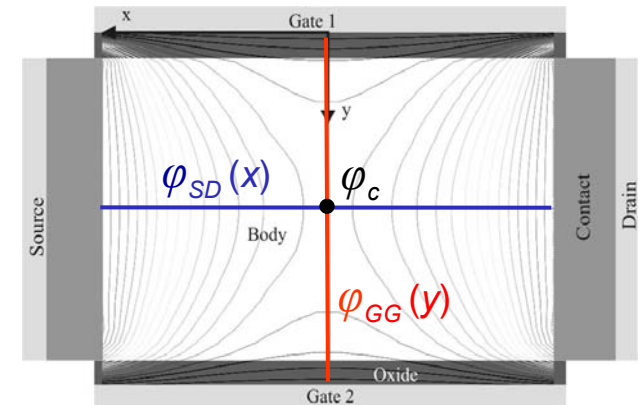
Procedure

Initiation

- Estimate center potential ϕ_c from long-channel limit.
- Approximate $\phi_{GG}(y)$ along G-G symmetry axis using long-channel limit.
- Establish modeling expression $\phi_{SD}(x)$ along S-D symmetry axis using boundary conditions near S and D drain and from center point
- From $\phi_{GG}(y)$ and $\phi_{SD}(x)$, establish approximate G-G distributions at different cut-lines.
- For finite V_{DS} , estimate a quasi-Fermi potential at the device center (for example, $V_{Fc} = V_{DS}/2$)

Processing

- Calculate current and update V_{Fc}
- Estimate $\phi''_{SD}(0)$ from $\phi_{SD}(x)$ and apply to Poisson's equation to update ϕ_c .
- Update $\phi_{GG}(y)$ and $\phi_{DS}(x)$
- Repeat until satisfactory accuracy is obtained (typically 3 iterations)



Threshold voltage:

Defined as V_{GS} for which

$$\phi_{GG}(y) = \text{const} = V_{FB}$$

when $V_{DS} = 0$ V. Find for our devices:

$$V_T(\text{DG}) = 0.25 \text{ V}$$

$$V_T(\text{GAA}) = 0.24 \text{ V}$$

Strong inversion

Gate-to-gate symmetry line

For DG MOSFET, use long-channel potential $\varphi_{GG}(y)$ from 1D Poisson's equation (Taur 2001), adjusted to include effects of body doping:

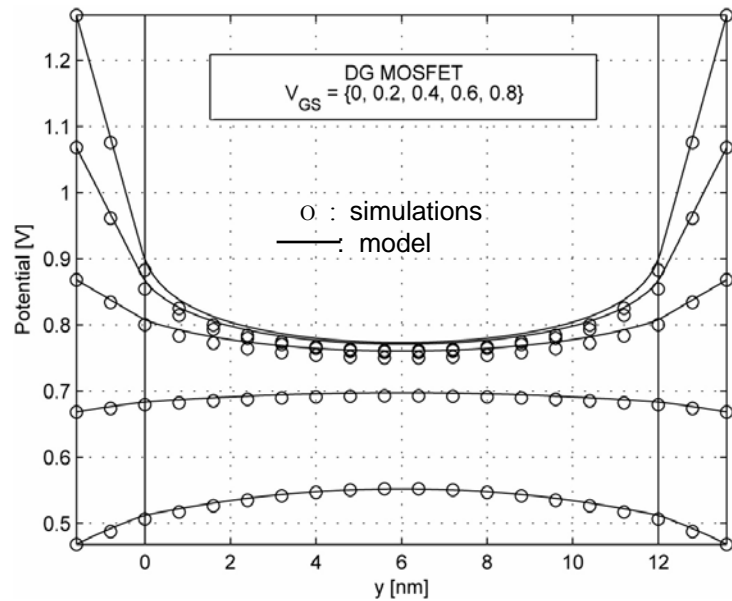
$$\varphi_{GG}(y) = \varphi_c - 2V_{th} \ln \left[\cos \left(\sqrt{\frac{qn_i}{2\epsilon_s V_{th}}} \exp \left(\frac{\varphi_c - \varphi_b}{2V_{th}} \right) (y - t'_{ox} - t_{Si}/2) \right) \right]$$

Correspondingly for GAA MOSFET (Iniguez 2005).

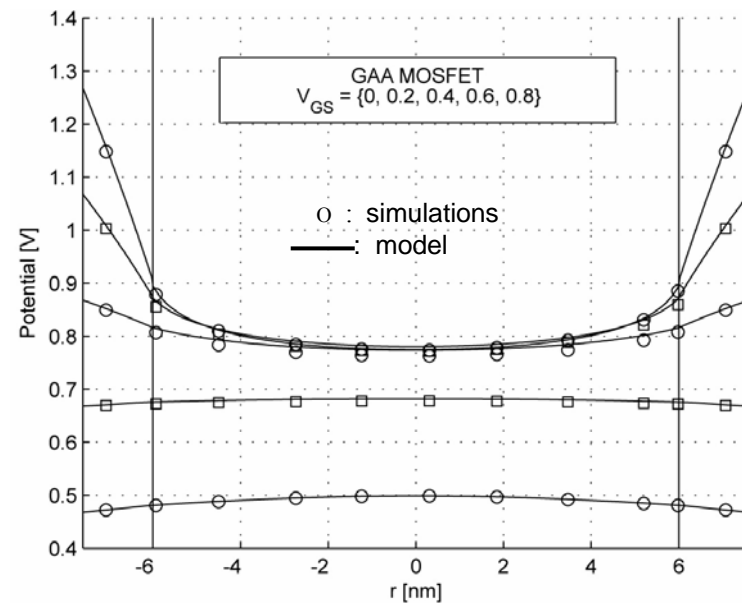
Note: Inter-electrode capacitive effects screened by adaption of the electron distribution.

$\varphi_{GG}(y)$ along G-G symmetry axis

DG



GAA

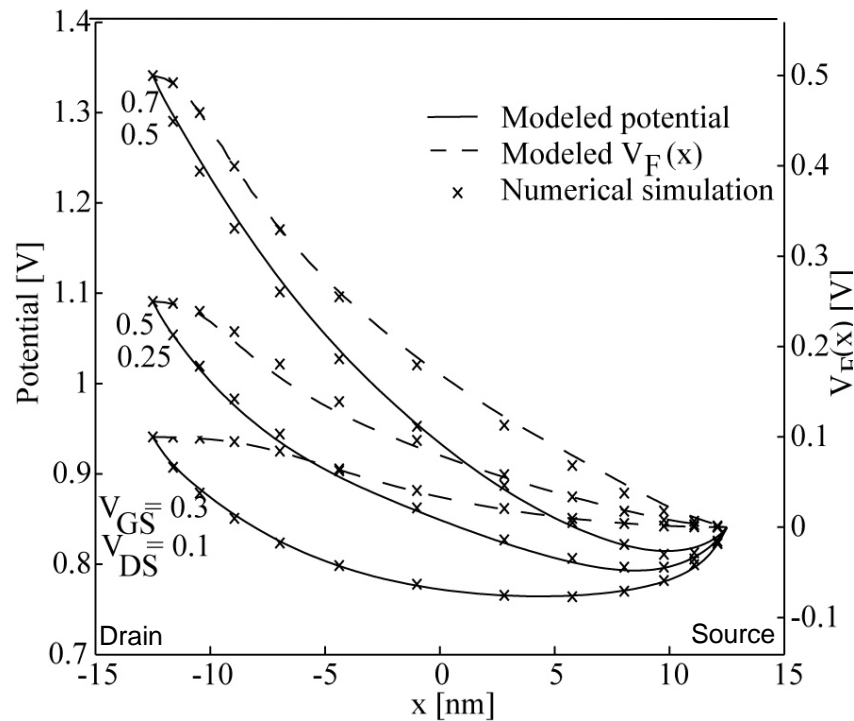


Central gate-to-gate pot. profiles vs. V_{GS} for $V_{DS} = 0$ V

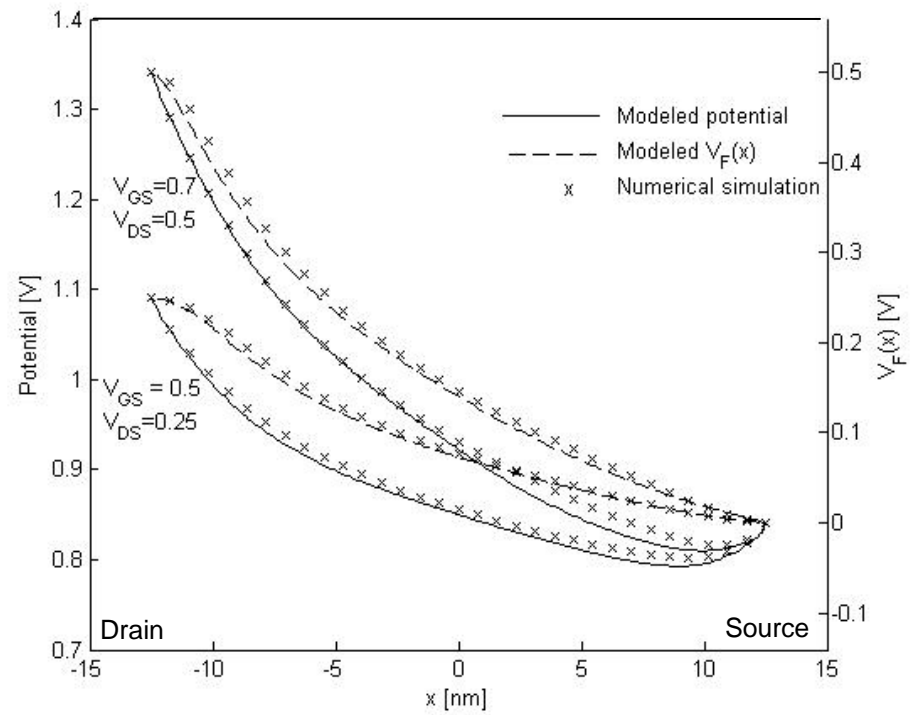


$\varphi_{DS}(x), V_F(x)$ along $D-S$ symmetry axis

DG

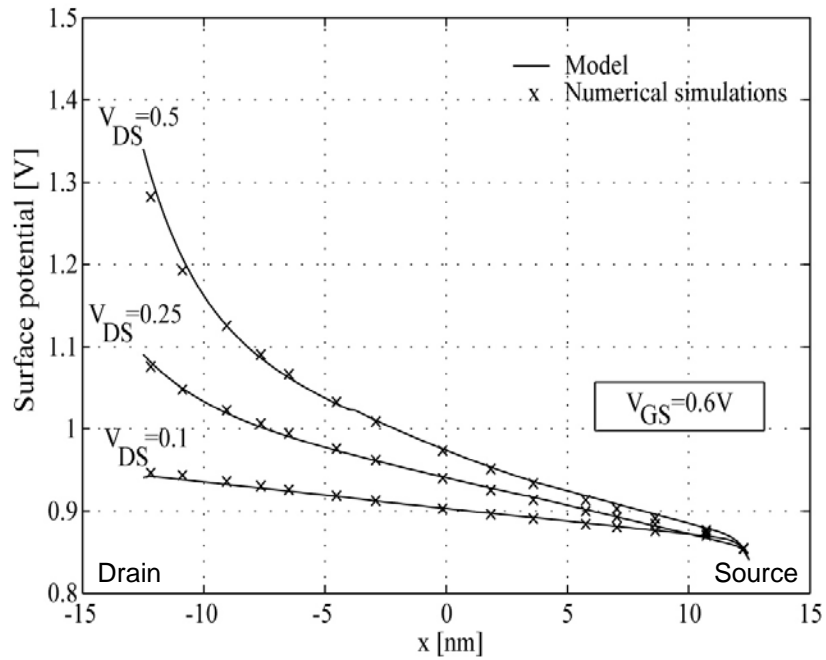


GAA

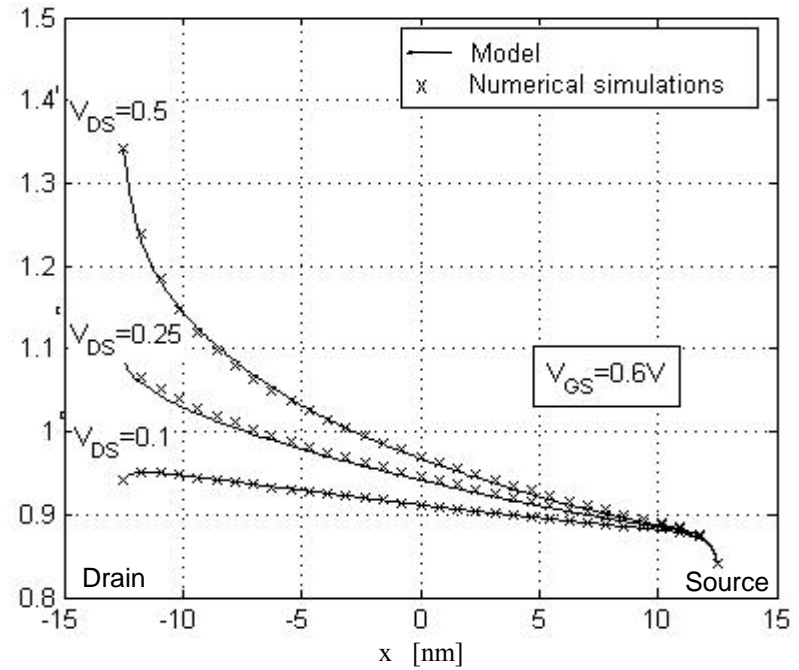


Interface potential in strong inversion

DG



GAA



Drain current modeling

Drift-diffusion transport:

Use electron density derived self-consistently in:

$$I_{DD} = -qW\mu_n n_s(x) \frac{dV_F(x)}{dx} = \frac{qW\mu_n V_{th} (1 - e^{-V_{DS}/V_{th}})}{\int_0^L \frac{dx}{n_{so}(x)}}$$

$n_{so}(x)$: surface concentration of electrons in all cross-sections from source to drain using $V_F(x) = \text{const.} = V_{FS}$.

Ballistic transport (not considered here):

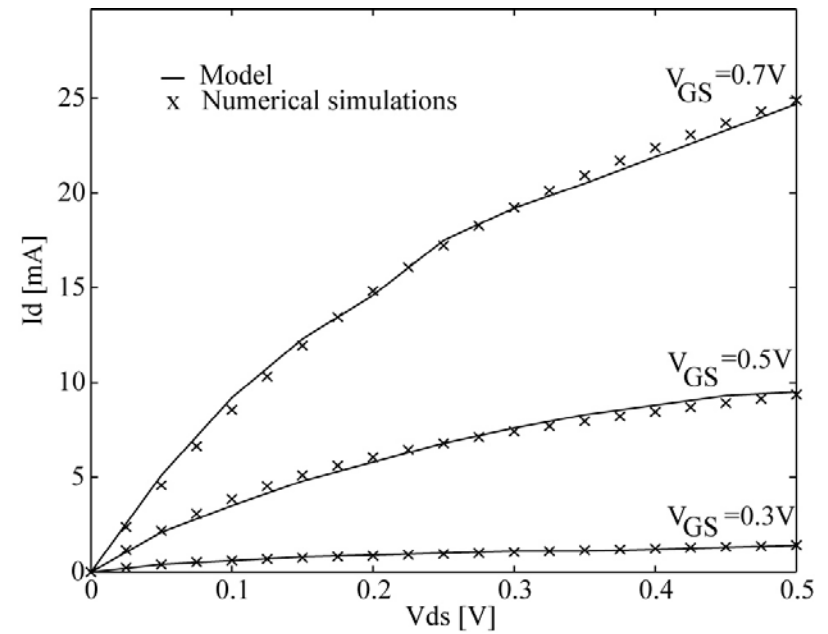
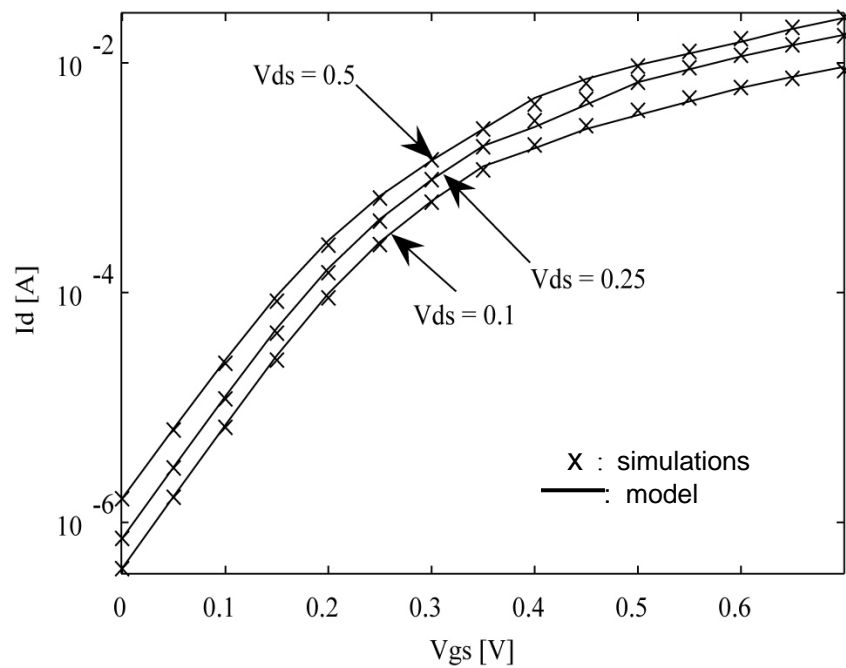
- Current consists of free-flight electrons with sufficient energy to fly over barrier
- Electrons 'filtered' through available quantum states at barrier position
- Current limited by ability of source and drain to supply high-energy carriers fast enough

Natori formalism (1994, 2002):

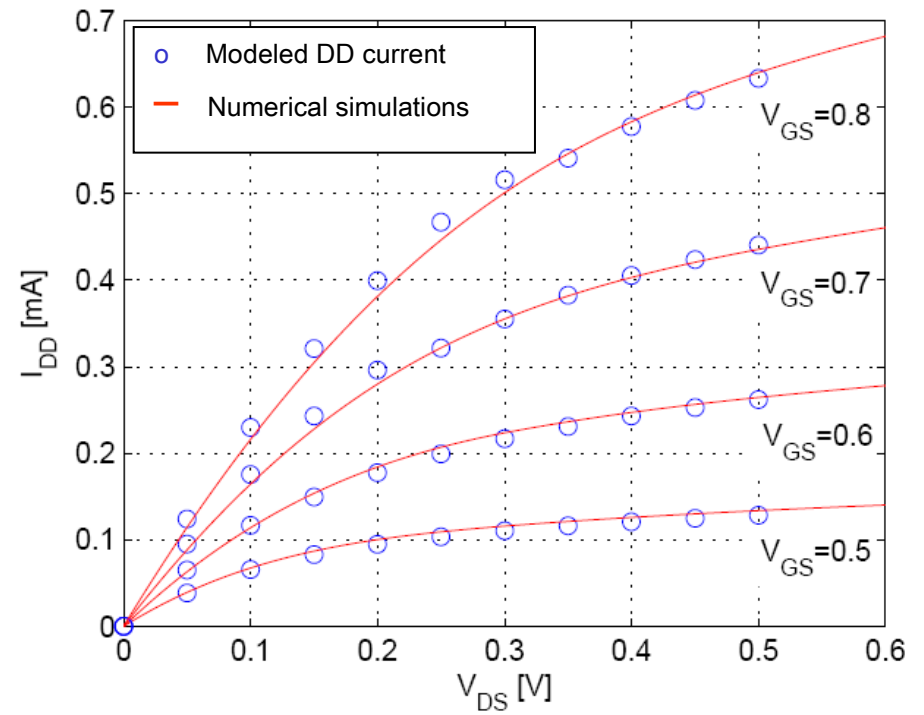
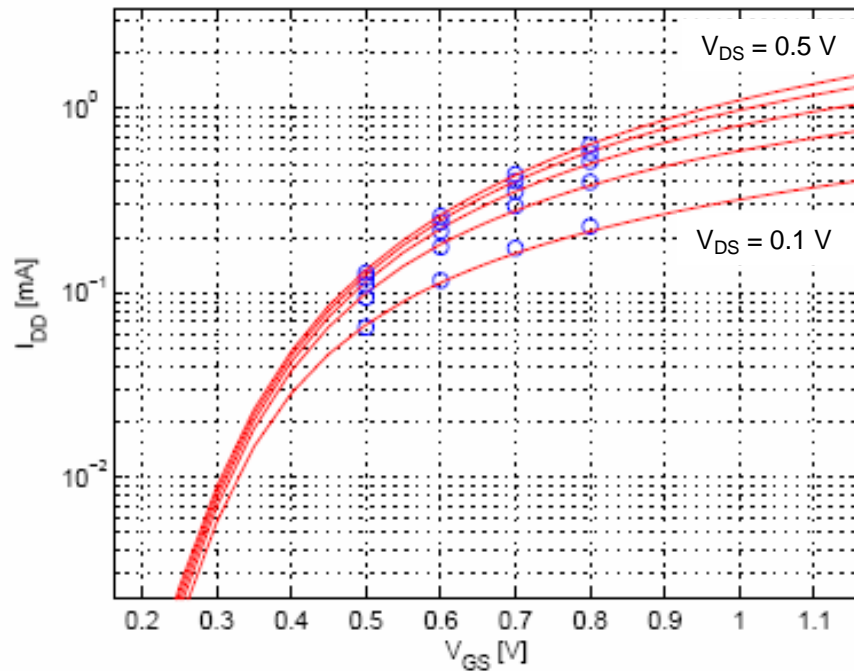
$$I_{BT} = q(F^+ - F^-) \quad \text{where} \quad F^\pm = \frac{(2k_B T)^{3/2}}{\pi^2 \hbar^2} \sum_{\text{valleys}} \sum_j \sqrt{m_i} F_{1/2} \left(\frac{E_{Fs} - E_{ij} - qV^\pm}{k_B T} \right)$$



Drain current modeling – DG MOSFET



Drain current modeling – GAA MOSFET



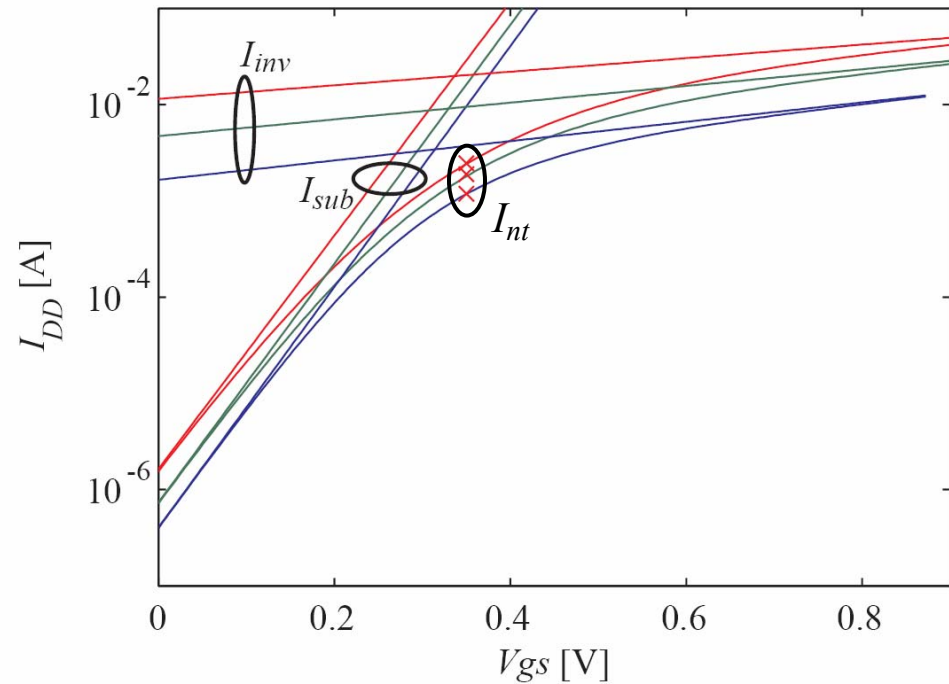
Compact modeling of drain current – example

'Generic' modeling expression

$$I_{DD} = 10^{\wedge} \left[\frac{\log(I_{sub})}{\left[1 + \left(\frac{\log(I_{sub})}{\log(I_{inv})} \right)^m \right]^{1/m}} \right]$$

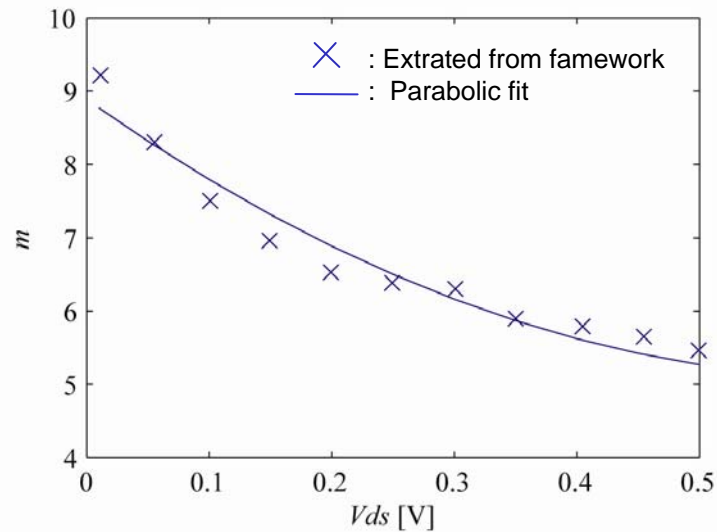
Procedure:

- Use limiting forms of I_{DD} in subthreshold (I_{sub}) and strong inversion (I_{inv})
- Calculate I_{DD} near threshold (I_{nt}) from modeling framework
- Use I_{nt} versus V_{GS} to determine the shape parameter $m(V_{GS})$



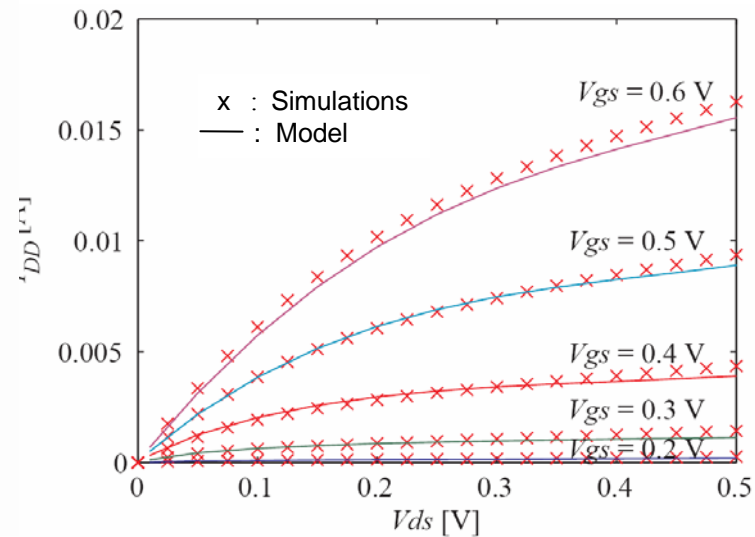
Compact modeling of drain current – DG MOSFET

Extraction of parameter m



Use least-squares fit of a second degree polynomial (3 parameters)

Resulting $I_{DD} - V_{DS}$ characteristics



Note: A better precision in m (more parameters) would give a better fit to the numerical modeling

Summary

Precise *modeling framework* established for short-channel, nanoscale DG and GAA MOSFETs featuring:

- *Full range of applied bias voltages*
- *Self-consistency*
- *Full potential and QFP distributions*
- *Drift-diffusion drain current*
- *No adjustable parameters*

Compact model expressions established with a minimal parameter set extractable from the framework

Models verified by numerical simulations (ATLAS/Silvaco)